

Attorney Docket: 040258-0307509
Client Reference: EL00022CDC-DIV

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:
KOMIYAMA ET AL.
Application No.:

Confirmation Number:

Group Art Unit: 2812

Filed: January 21, 2004

Examiner:

Title: DEVICE AND METHOD FOR MONITORING PROCESS EXHAUST GAS,
SEMICONDUCTOR MANUFACTURING DEVICE, AND SYSTEM AND METHOD FOR
CONTROLLING SEMICONDUCTOR MANUFACTURING DEVICE

PRELIMINARY AMENDMENT

Mail Stop Non-Fee Amendments
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Before beginning examination, please amend the above-referenced divisional
application as follows: